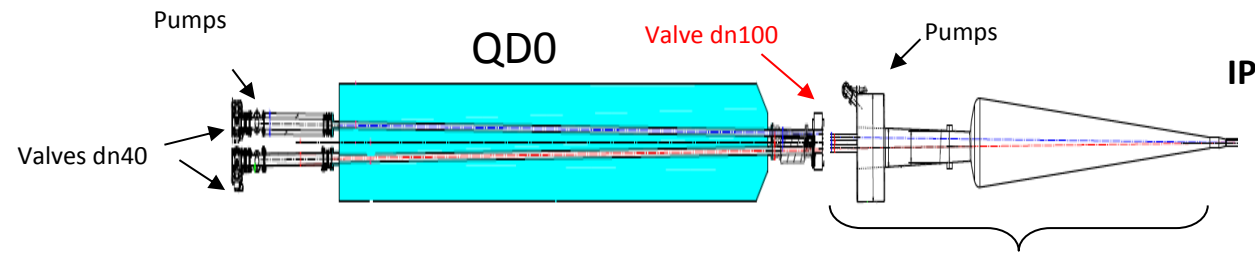
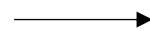


possible changes towards $L^*=4m$



Need a pumping system between the two DN 100 valves (hot part of the IP chamber)

Proposal for a distributed pumping: coating NEG (Non evaporate Getter)



Length reduction



Improved vacuum level (to quantify)



Need to in situ baking of beam pipe

Dynamic pressure

Gas desorption needs to be studied for the IP vacuum consideration.

Photon , ion and electron desorption

E-cloud

Lost electron positron

working proposals

Simulation with distributed pumps NEG under static pressure (without lumped pump)

Informations about particles flow striking the surface per unit length

Geometry QDO chamber ? Magnet feature, beam size, Beam screen, sticking coefficient,